

## TRANSMITTAL

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<b>Title of Invention</b>	HIGH-PRESSURE PROCESSING CHAMBER FOR A SEMICONDUCTOR WAFER	
Application Number :	10/680783	
Date :	2003-10-06	
First Named Applicant:	Jones William Dale	
Confirmation Number:	5859	
Attorney Docket Number:		
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<b>Documents being submitted:</b>	<b>Files</b>
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<b>Comments</b>	